

AF  
ZJM

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Kie Y. Ahn et al.  
Title: ATOMIC LAYER-DEPOSITED LaAlO<sub>3</sub> FILMS FOR GATE DIELECTRICS  
Docket No.: 1303.050US2  
Filed: February 27, 2004  
Examiner: N. Drew Richards



Serial No.: 10/789,042  
Due Date: November 6, 2006  
Group Art Unit: 2815

**MS AF**  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

We are transmitting herewith the following attached items (as indicated with an "X"):

Return postcard.  
 Amendment and Response Under 37 CFR 1.116 (15 pgs.).  
 Communication Concerning Related Applications (2 pgs.).

If not provided for in a separate paper filed herewith, Please consider this a PETITION FOR EXTENSION OF TIME for sufficient number of months to enter these papers and please charge any additional fees or credit overpayment to Deposit Account No. 19-0743.

SCHWEGMAN, LUNDBERG, WOESSNER & KLUTH, P.A.  
Customer Number 21186

By: David R. Cochran  
Atty: David R. Cochran  
Reg. No. 46,632

CERTIFICATE UNDER 37 CFR 1.8: The undersigned hereby certifies that this correspondence is being deposited with the United States Postal Service with sufficient postage as first class mail, in an envelope addressed to: MS AF, Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450, on this 6 th day of November, 2006.

David R. Cochran

Name

Signature

SCHWEGMAN, LUNDBERG, WOESSNER & KLUTH, P.A.  
(GENERAL)

EXPIRED PROCEDURE - EXAMINING GROUP 2815

S/N 10/789,042

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Kie Y. Ahn et al.

Examiner: N. Drew Richards

Serial No.: 10/789,042

Group Art Unit: 2815

Filed: February 27, 2004

Docket No.: 1303.050US2

Title: LaAlO<sub>3</sub> FILMS (as amended)

AMENDMENT & RESPONSE UNDER 37 C.F.R. 1.116

Mail Stop AF  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

In response to the Final Office Action dated September 5, 2006, please amend the application as follows:

**IN THE TITLE**

**Please amend the previously amended title as follows:**

**ATOMIC LAYER DEPOSITED LaAlO<sub>3</sub> FILMS**